

Highly sensitive flexible capacitive pressure sensor based on micro-arrayed polydimethylsiloxane dielectric layer

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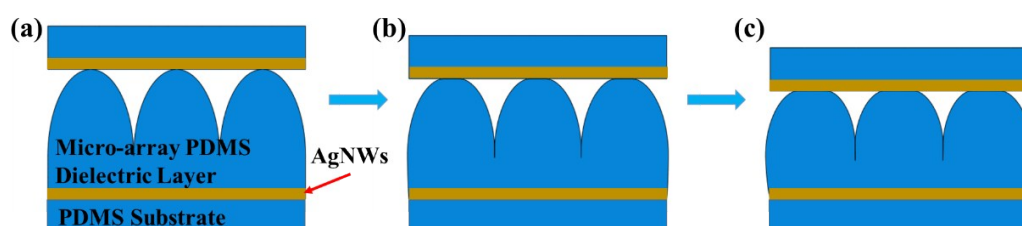


Fig. S1 Deformation process of micro-arrayed PDMS under pressure

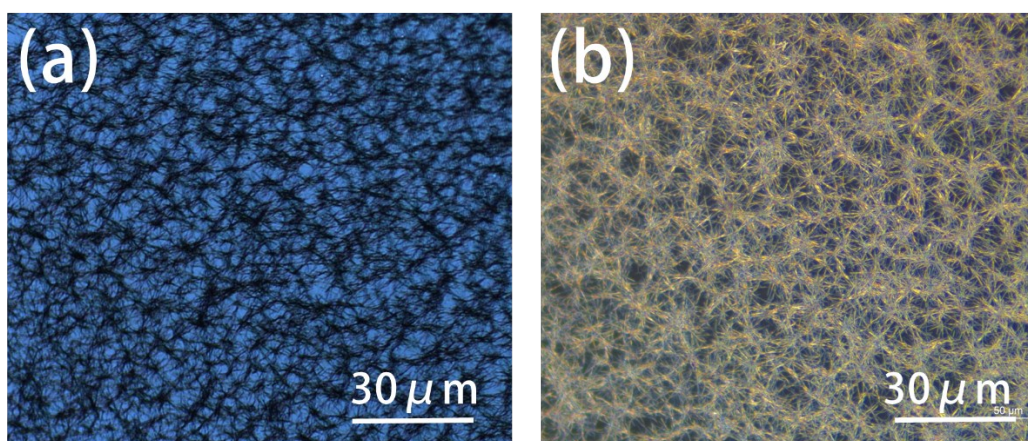


Fig. S2 Optical microscope images of the PDMS flexible electrode

Table 1. The influence of the dosage of AgNWs in the flexible electrodes on their conductivity and transparency

Number	Dosage of AgNWs ($\mu\text{g cm}^{-2}$)	Sheet resistance ($\Omega \text{ sq}^{-1}$)
a	10	18.78
b	15	8.84
c	20	2.75
d	30	1.64
e	40	0.97
f	50	0.58

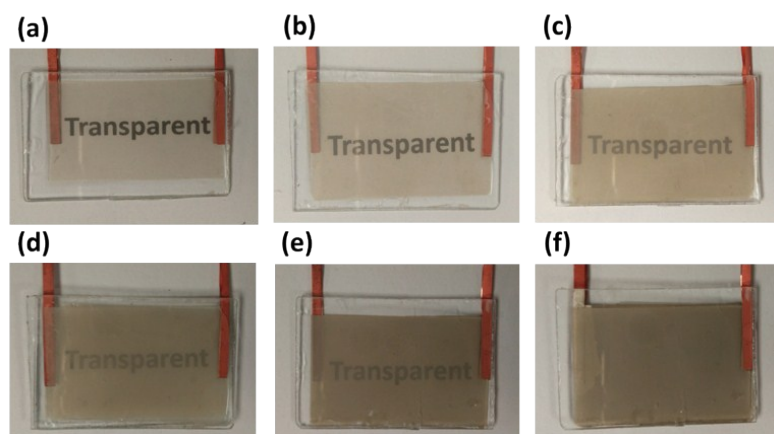


Fig. S3 The photographs of the pressure sensors fabricated by different flexible electrodes. (a) a; (b) b; (c) c; (d) d; (e) e; (f) f.

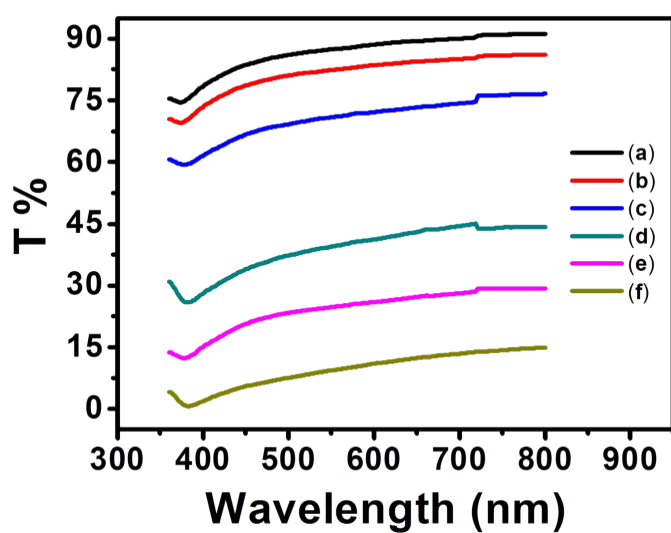


Fig. S4 The transmittance curves of different flexible electrodes to the visible light. (a) a; (b) b; (c) c; (d) d; (e) e; (f) f.

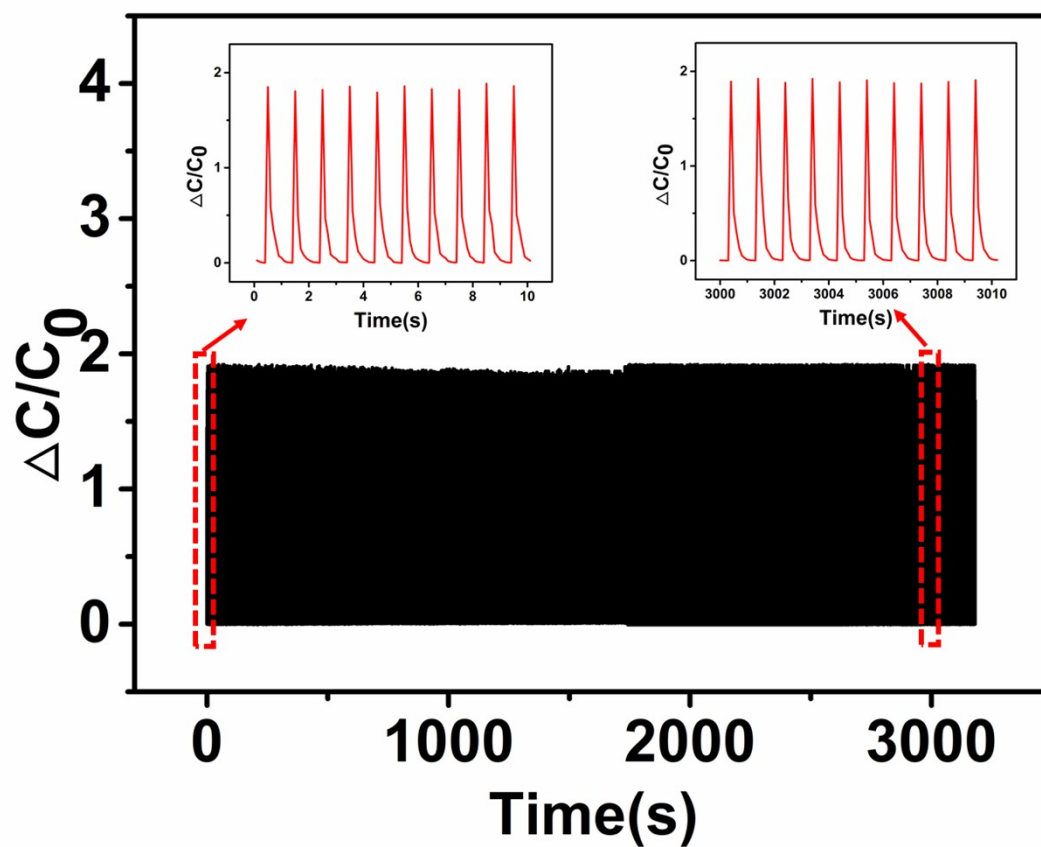


Fig. S5 Pressure response of the sensor after more than 3000 cycles pressurization test, the inset shows 10 cycles at the beginning and the 3000th.